TTC meeting 2018 at RIKEN Nishina Center

Friday 29 June 2018

Special Seminar Session - RIBF Main Conference Room (11:00 - 12:30)

-Conveners: Eiji Kako (KEK)

time	[id] title	presenter
11:00	[115] Industrial applications in compact-ERL at KEK: EUV light source for semiconductor lithography, Mo-99 production for medical application, and Non-destructive inspection for nuclear security system	KAWATA (KEK), Hiroshi
11:45	[116] Next generation high intensity neutron source at QST-Rokkasho; A-FNS	SAKAMOTO (QST), Keishi